

PARTIAL TRANSLATION OF JAPANESE UNEXAMINED PATENT PUBLICATION  
(KOKAI) No. H05(1993)-309231

Title of the Invention: Apparatus of treating exhaust gas

Application No.: H04(1992)-118987

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Applicant: Mitsubishi Heavy Ind. Ltd.

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[Brief Explanation of Drawings]

[Fig. 1]

A schematic view of a structure of one embodiment of the present invention.

[Fig. 2]

A sectional view of the reaction vessel portion of the above embodiment.

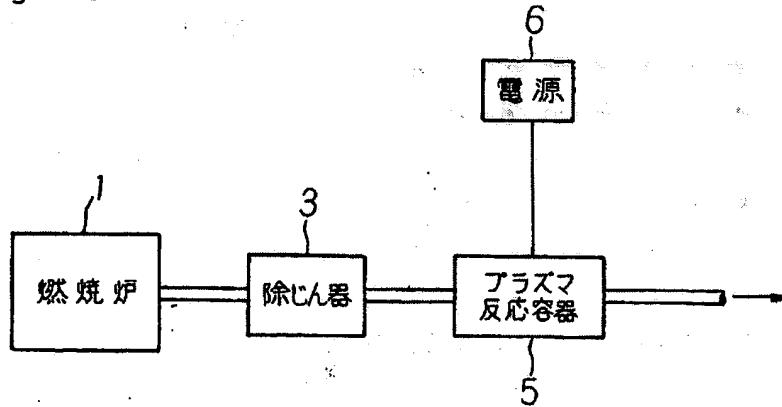
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[Explanation of Reference Numbers]

- 1 ... combustion furnace;
- 3 ... dust preventing device;
- 5 ... plasma reaction vessel;
- 6 ... electric power supply;
- 18 ... inlet tube for exhaust gas;
- 51 ... reaction vessel (housing main body);
- 52 ... electrode;
- 53 ... dielectric material.

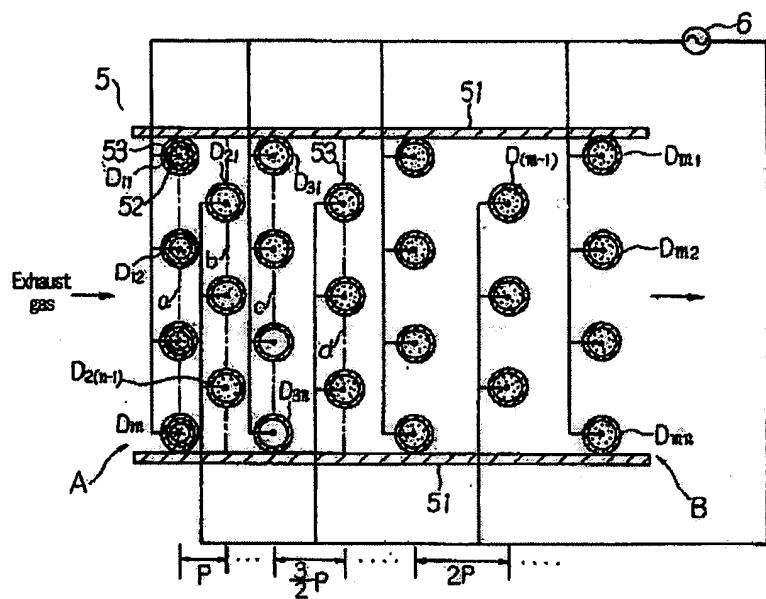
[Drawings]

[Fig. 1]



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[Fig. 2]



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